Rules for Optical Testing

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Rules for Optical Metrology

Based on 30 years of optical testing experience, a lot of mistakes, a lot of learning and a lot of experience,

I have defined seven guiding principles for optical testing – regardless of how small or how large the optical testing or metrology task

GUIDING PRINCIPLES

1. Fully Understand the Task
2. Develop an Error Budget
3. Continuous Metrology Coverage
4. Know where you are
5. ‘Test like you fly’
6. Independent Cross-Checks
7. Understand All Anomalies

These rules have been applied with great success to the in-process optical testing and final specification compliance testing of the JWST mirrors.
Rule #1: Fully Understand the Task

Make sure that you fully understand your task:
who is your customer;
what parameters do you need to quantify;
to what level of uncertainty you must know their value; and
who is your manufacturing interface?

Before accepting any testing task, study your customer’s requirements and understand how they relate to the final system application.

Then summarize all requirements into a simple table which can be shared with your customer and your manufacturing methods engineer.

Make sure that your customer agrees that what you will quantify satisfies their requirements and the manufacturing methods engineer agrees that they can make the part based upon the data you will be providing.

JWST is Customer making Segmented PM

- Secondary Mirror Support Structure (SMSS)
- Primary Mirror Segment Assemblies (PMSA)
- BackPlane
- ISIM Enclosure
- ISIM Electronics Compartment (IEC)
- Deployment Tower Subsystem
- Secondary Mirror Assembly (SMAA)
  - Light-weighted, rigid Be mirror
  - Hexapod actuator
  - Stray light baffle
- OTE Clear Aperture: 25 m²
- JWST is Customer making Segmented PM
JWST Optical Testing Needs

The principle JWST optical testing needs include:

Optical Component Assemblies
- Primary Mirror Segment Assembly (PMSA) 18 + 3 spares
- Secondary Mirror Assembly (SMA) 1 + 1 spare
- Tertiary Mirror Assembly (TMA) 1

Observatory Elements
- Primary Mirror Assembly (PMA)
- Optical Telescope Element (OTE)

Additionally, there are multiple other optics such as the fine steering mirror and various instrument optical components.

Optical Component Configurations

There are 3 mirror configuration ‘states’:
- Configuration 1 = Substrate Only
- Configuration 2 = Flight Flexures & Whiffle and Surrogate Delta Frame
- Configuration 3 = Flight
All Components have Cryogenic Performance Specifications

Since components are fabricated at Ambient it is necessary to Cryo-Null Figure, i.e. compensate for ambient to cryo changes

All Components have:

- an Initial Requirement which must be met before Cryo-Testing
- a Final Post Cryo-Null Figuring Requirement, and
- a Final Cryogenic Performance Requirement

### JWST Optical Component Specifications

#### Segment Fabrication Requirements & Tolerances

<table>
<thead>
<tr>
<th>Parameter</th>
<th>Specification</th>
<th>Tolerance</th>
<th>Units</th>
<th>Comments</th>
</tr>
</thead>
<tbody>
<tr>
<td><strong>Requirements for initial figuring</strong></td>
<td></td>
<td></td>
<td></td>
<td></td>
</tr>
<tr>
<td>Clear Aperture (based on Edge Specification)</td>
<td>1.4776</td>
<td>Minimum</td>
<td>mm²</td>
<td>*Different for 3 segments</td>
</tr>
<tr>
<td>Scratch-Dig</td>
<td>80-50</td>
<td>Maximum</td>
<td></td>
<td></td>
</tr>
<tr>
<td>Conic Constant</td>
<td>-0.99666</td>
<td>+/- 0.0010</td>
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<tr>
<td>Radius of Curvature</td>
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<td>+/- 1</td>
<td>mm</td>
<td></td>
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<tr>
<td>Prescription Alignment Error</td>
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<td></td>
<td></td>
<td></td>
</tr>
<tr>
<td>Decenter</td>
<td>*</td>
<td>≤ 0.35</td>
<td>mm</td>
<td>*Different for 3 segments</td>
</tr>
<tr>
<td>Clocking</td>
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<td>≤ 0.35</td>
<td>mrad</td>
<td></td>
</tr>
<tr>
<td>Piston</td>
<td>N/A</td>
<td></td>
<td></td>
<td>Measure only, no requirement</td>
</tr>
<tr>
<td>Tilt</td>
<td>N/A</td>
<td></td>
<td></td>
<td>Measure only, no requirement</td>
</tr>
<tr>
<td><strong>Total Surface Figure Error:</strong></td>
<td></td>
<td></td>
<td></td>
<td></td>
</tr>
<tr>
<td>Low/Mid Frequency (≤222 mm/cycle)</td>
<td>150</td>
<td>Maximum</td>
<td>nm rms</td>
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<tr>
<td>High Frequency (222 to 0.08mm/cycle)</td>
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<td>Maximum</td>
<td>nm rms</td>
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<tr>
<td>Slope Error</td>
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<td>Maximum</td>
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<tr>
<td><strong>Requirements for cryo-null figuring</strong></td>
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<td></td>
</tr>
<tr>
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<td>Minimum</td>
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<tr>
<td>Radius of Curvature</td>
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<td>nm rms</td>
<td>Relative to cryo-target map</td>
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<td>High Frequency (222 to 0.08mm/cycle)</td>
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<td>nm rms</td>
<td>Relative to cryo-target map</td>
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<td>PSD Spike Requirement</td>
<td>Spikes Limit</td>
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<tr>
<td>Surface Roughness</td>
<td>4</td>
<td>Maximum</td>
<td>nm rms</td>
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Metrology Plan for Each Requirement

<table>
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<tr>
<th>Parameter</th>
<th>Spec</th>
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<th>Units</th>
<th>Verification</th>
<th>Validation</th>
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<tr>
<td>Clear Aperture (Edge Specification)</td>
<td>1.4776</td>
<td>Min (5)</td>
<td>mm^2</td>
<td>Measure edges at ambient using Tinsley HS Interferometer</td>
<td>Measure area at cryo using XR CF CoC Interferometer</td>
</tr>
<tr>
<td>Scratch-Dig</td>
<td>80-50</td>
<td>Max</td>
<td>mm</td>
<td>Ambient Visual Inspection</td>
<td>Independent Visual</td>
</tr>
<tr>
<td>Conic Constant</td>
<td>-0.99666</td>
<td>+/- 0.0005</td>
<td>Measured at cryo and defined by null geometry for XR CF CGH CoC test</td>
<td>Ambient test at Tinsley, compare CGH CoC test with autocollimation test</td>
<td></td>
</tr>
<tr>
<td>Radius of Curvature</td>
<td>*</td>
<td>+/- 0.15</td>
<td>mm</td>
<td>Set at XR CF using ADM</td>
<td>ROCO Comparison</td>
</tr>
<tr>
<td>Prescription Alignment Error</td>
<td>Decenter</td>
<td>*</td>
<td>+/- 0.35</td>
<td>mm</td>
<td>Cryogenic test at XR CF, defined by residual wavefront error relative to CGH CoC test and fiducial alignment</td>
</tr>
<tr>
<td></td>
<td>Clocking</td>
<td>0</td>
<td>+/- 0.35</td>
<td>mrad</td>
<td></td>
</tr>
<tr>
<td>Piston</td>
<td>N/A</td>
<td>Ambient CMM measurement at AXSYS</td>
<td></td>
<td></td>
<td>Ambient CMM measurement at Tinsley</td>
</tr>
<tr>
<td>Tilt</td>
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<td></td>
<td></td>
<td></td>
<td></td>
</tr>
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<td>Total Surface Figure Error:</td>
<td>Low/Mid Frequency</td>
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<td>Max</td>
<td>nm rms</td>
<td></td>
</tr>
<tr>
<td>Surface Roughness</td>
<td>4</td>
<td>Max</td>
<td>nm rms</td>
<td></td>
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</tr>
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</table>

Lesson Learned Example

A simple example of how not ‘fully understanding the task’ causes trouble is Zernike polynomial coefficients.

Optical designers use Zernike coefficients to specify components and metrologists use Zernike coefficients to describe surface shape. But, which Zernike coefficients? Also, PV or RMS?

Design software typically use B&W while Interferometer software typically use Fringe. Orders are different.
Lesson Learned Example

Also, some designers and fabricators use PV Zernike Coefficients and some use RMS.

Optical designers use Zernike coefficients to specify components and metrologists use Zernike coefficients to describe surface shape. But, which Zernike coefficients? Also, PV or RMS?

Table 1. Zernike Polynomial Coefficient Index (first 8 coefficients only)

<table>
<thead>
<tr>
<th>Description</th>
<th>Polynomial</th>
<th>ISO</th>
<th>FRINGE</th>
<th>Born &amp; Wolfe</th>
<th>Kodak</th>
<th>RMS to PV Ratio</th>
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<tbody>
<tr>
<td>Piston</td>
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<td>0</td>
<td>1</td>
<td>1</td>
<td>0</td>
<td>1</td>
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<tr>
<td>X-Tilt r cosθ</td>
<td>2</td>
<td>3</td>
<td>4</td>
<td>5</td>
<td>3</td>
<td>1/sqrt(3)</td>
</tr>
<tr>
<td>Y-Tilt r sinθ</td>
<td>2</td>
<td>3</td>
<td>3</td>
<td>2</td>
<td>1</td>
<td>1</td>
</tr>
<tr>
<td>Power</td>
<td>2r - 1</td>
<td>3</td>
<td>4</td>
<td>5</td>
<td>3</td>
<td>1/sqrt(3)</td>
</tr>
<tr>
<td>X-Astigmatism</td>
<td>r cos2θ</td>
<td>4</td>
<td>5</td>
<td>4</td>
<td>3</td>
<td>1/sqrt(3)</td>
</tr>
<tr>
<td>Y-Astigmatism</td>
<td>r sin2θ</td>
<td>5</td>
<td>6</td>
<td>6</td>
<td>5</td>
<td>1/sqrt(3)</td>
</tr>
<tr>
<td>X-Coma (3r - 2) r cosθ</td>
<td>6</td>
<td>7</td>
<td>8</td>
<td>6</td>
<td>5</td>
<td>1/sqrt(3)</td>
</tr>
<tr>
<td>Y-Coma (3r - 2) r sinθ</td>
<td>7</td>
<td>8</td>
<td>9</td>
<td>7</td>
<td>5</td>
<td>1/sqrt(3)</td>
</tr>
<tr>
<td>Spherical</td>
<td>6r^4 - 4r^2 + 1</td>
<td>8</td>
<td>9</td>
<td>13</td>
<td>10</td>
<td>1/sqrt(5)</td>
</tr>
</tbody>
</table>

Rule #2: Develop an Error Budget

Develop an error budget for every specification & tolerance.

Error budget predicts test accuracy and reproducibility (not repeatability) of the metrology tools.

Reproducibility is the ability of ‘independent’ measurement executions to achieve the same answer, e.g. take down and re-set a test.

All elements of error budget must be certified by absolute calibration and verified by independent test.

An error budget has multiple functions.

Convinces your customer that you can actually measure the required parameters to the required tolerances;
Defines which test conditions have the greatest impact on test uncertainty;
Provides a tool for monitoring the test process.

If the variability in the test data exceeds the error budget prediction, then you must stop and understand why.
Error Budget Contingency

An Error Budget **MUST** have Contingency Reserve.

No matter how much one thinks about every potential contingency risk or how careful one executes, errors happen.

Three examples of mirrors fabricated according to an error budget – which were in fact better than the error budget until an error occurred. Because of Reserve, they all met their final requirement specification.

On Spitzer, the assembled telescope was well below its requirement until the shake test. A bolt hole which was not deep enough introduced forces which bent the Primary Mirror (by approx 1/3rd of its requirement). But, the total system still met spec.

On JWST, as the primary mirror segment fabrication process improved, the segments were greatly below their requirement. But, an incorrect calibration file was used on two PMSAs resulting in residual excess power (of approx 1/3rd of its figure requirement). But, the primary mirror still met spec.

On JWST, the secondary mirror’s ambient surface figure error was well below its requirement. But, metal tape used to attach the thermal couples to the secondary mirror during its cryo test introduced a residual error into the cryo-hit map (of approx 1/3rd of its figure requirement). But, the primary mirror still met spec.

A good value for Error Budget Reserve is 33% of the Requirement.

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**JWST PMSA Error Budget**

<table>
<thead>
<tr>
<th>Specification</th>
<th>Error Budget</th>
</tr>
</thead>
<tbody>
<tr>
<td>Tolerance</td>
<td>0.001 mm</td>
</tr>
<tr>
<td>Value</td>
<td>0.001 mm</td>
</tr>
<tr>
<td>Deviation</td>
<td>0.001 mm</td>
</tr>
<tr>
<td>Total</td>
<td>0.001 mm</td>
</tr>
</tbody>
</table>

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**JWST PMSA Error Budget**

<table>
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</tr>
<tr>
<td>Deviation</td>
<td>0.001 mm</td>
</tr>
<tr>
<td>Total</td>
<td>0.001 mm</td>
</tr>
</tbody>
</table>
Tinsley Test Reproducibility
(OTS-1 Test #1 vs. Test #2) VC6GA294-VC6HA270

Power
(Radius Delta: 0.02 mm)

Astigmatism:
4.4 nm RMS

Mid Frequency:
4.3 nm RMS

High Frequency:
3.9 nm RMS

Total Surface Delta:
PV: 373 nm
RMS: 7.6 nm

BATC to Tinsley Initial Comparison too large

Initially, BOTS and TOTS Radius did not agree. Discrepancy was determined to be caused by bulk temperature difference. Agreement is now at 10 nm rms level.
Develop an Error Budget

To correct way to develop an error budget is to perform a propagation of error analysis.

Start with the equation which defines how the requirement is calculated from the measured parameters.

Propagation of error connects the uncertainty of the calculated parameter to the uncertainty of the measured quantities.

\[
\sigma_R = \sqrt{\left( \frac{\delta f(a, b, c)}{\delta a} \right)^2 \sigma_a^2 + \left( \frac{\delta f(a, b, c)}{\delta b} \right)^2 \sigma_b^2 + \left( \frac{\delta f(a, b, c)}{\delta c} \right)^2 \sigma_c^2}
\]
Lesson Learned – validate error budget early

On ITTT program (which became Spitzer) I was SM engineer. I had a complete error budget, but some elements were allocations. Secondary Mirror was manufactured to a Hindle sphere test and the optician achieved an excellent result. Unfortunately, I didn’t calibrate the Hindle sphere until it was time to perform the final certification and it had a trefoil mount distortion. Because SM had a three point mount, every time it was tested, the bumps on the SM exactly matched the holes in the Hindle sphere. Fortunately, it still met specification; it was just not spectacular.

Moral of the story:
- Validate your error budget early, and
- As much as possible, randomize your alignment from test to test.

Sometimes bad things happen from been too meticulous. (This could almost be an 8th rule.)

Rule #3: Continuous Metrology Coverage

Third, have continuous metrology coverage:
- ‘you cannot make what you cannot test’
- (or ‘if you can test it then you can make it’).

Every step of the manufacturing process must have metrology feedback and there must be overlap between the metrology tools for a verifiable transition.

Failure to implement this rule typically results in one of two outcomes:
- very slow convergence, or
- negative convergence.
Optical Component Manufacturing Flow

Manufacturing flow is nearly identical for all optical components

There are Metrology ‘Gates’ between each processing step. Components must meet their requirements to go to the next step.

Continuous Metrology Coverage

JWST developed overlapping tools to measure & control
conic constant,
radius of curvature,
prescription alignment and surface figure error
throughout the fabrication process.

During rough grinding, used a Leitz Coordinate Measuring Machine (CMM) for radius of curvature & conic constant.

During polishing, meterololgy was provided by a Center of Curvature (CoC) interferometric test.
Leitz CMM

CMM was sized to test PMSA Full Aperture

Full Aperture Optical Test Station (OTS)

Center of Curvature Null Test measured & controlled:
  Prescription,
  Radius &
  Figure

Results are cross-checked between different 2 test stations.
Continuous Metrology Coverage

Ordinarily, optical fabricators try to move directly from CMM to optical test during fine grinding. But, given the size of JWST PMSAs and the mid-spatial frequency specification, this was not possible.

Bridge data was provided by a Wavefront Sciences Scanning Shack Hartmann Sensor (SSHS).

Its infrared wavelength allowed it to test surfaces in a fine grind state. And, its large dynamic range (0 to 4.6 mrad surface slope), allowed it to measure surfaces which were outside the interferometer’s capture range.

Wavefront Sciences Scanning Shack-Hartmann

SSHS provided bridge-data between grind and polish, used until PMSA surface was within capture range of interferometry

SSHS provide mid-spatial frequency control: 222 mm to 2 mm
Large dynamic range (0 – 4.6 mr surface slope)

When not used, convergence rate was degraded.
Comparison (222 - 2 mm spatial periods) 8/1/06

Smooth grind

SSHS
4.7 µm PV, 0.64 µm RMS

CMM
4.8 µm PV, 0.65 µm RMS

Point-to-Point Subtraction: SSHS - CMM = 0.27 µm RMS

Rule #4: Know where you are

It might seem simple, but if you don’t know where a feature is located on the mirror, you cannot correct it. This requires fiducials.

There are two types of fiducials: Data Fiducials and Distortion Fiducials.

Data fiducials are used to define a coordinate system and locate the measured data in that coordinate system. Sometimes this coordinate system is required to subtract calibration files, other times it is required to produce hit maps.

Distortion fiducials are used to map out test setup pupil distortion. Many test setups, particularly those with null optics can have radial as well as lateral pupil distortion. Distortion can cause tool misregistration errors of 10 to 50 mm or more.
Fiducials

Fiducials can be as simple as a piece of tape or ink marks on surface under test or as sophisticated as mechanical ‘fingers’ protruding into clear aperture.

For computer controlled processes, fiducial positional knowledge is critical.

Because test setups might invert or flip the imaging, I highly recommend an asymmetric pattern. The pattern which I have always used is:
- 0/180 degree fiducials produce a central axis for the data set,
- 90 degree fiducial defines left/right, and
- 30 degree fiducial defines top/bottom.

For rotationally symmetric systems, one option for distortion fiducials is multiple marks along a radius.

But for asymmetric systems, a grid of marks is required.

Finally, if you have a clear aperture requirement, place marks inside and outside of the required clear aperture.

Master Datums and Fiducials

Mirrors are manufactured in Observatory Coordinate Space as defined by ‘Master Datums’ on back of each mirror substrate.

Figure error is measured using ‘Data Fiducials’ on front of each mirror which are registered to ‘Transfer Fiducials’ (tooling balls) on the side of each mirror.
Master Datums and Fiducials

Data, Distortion and Edge Fiducials are used for PMSA testing.

Transfer Fiducials register these to the Master Datums on back.

This knowledge is critical because of redundancy between alignment errors and surface figure errors.

Lesson Learned

Another problem is software coordinate convention.

Most interferometer analysis software assumes that the optical (Z axis) positive direction points from the surface under test towards the interferometer, such that a feature which is higher than desired is positive.

But, many optical design programs define the positive optical axis to be into the surface.

The problem occurs because both programs will typically define the Y-axis as being up, so it is critical to understand which direction is +X-axis. (I have actually seen a software program which used a left handed coordinate system)

The problem is further complicated when interfacing with the optical shop. You must know the coordinate system of every computer controlled grinding and polishing machine.
Rule #5: ‘Test like you fly’

You must ‘Test like you fly’.

JWST operates in the cold of space. Therefore, we must certify 30K optical performance in the MSFC XRCF, and ‘zero-g’ performance via a 6 rotation test at BATC BOTS.

Observatory level qualification < 50K is done at JSC Chamber A.

Also, ‘test as you fly’ is not limited to space telescopes. Ground based telescopes can have large gravity sags.

Therefore, they must be tested in their final structure (or a surrogate).

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PMSA Flight Mirror Testing at MSFC XRCF

Cryogenic Performance Specifications are Certified at XRCF

Because JWST mirrors are fabricated at room temperature (300K) but operate < 50K, their shape change from 300 K to 30K is measured to generate a ‘hit-map’, and cryo-null polish the mirrors.
JWST Flight Mirror Test Configuration

Table and Stand-Offs

Facility Optical Axis

Facility Floor

Table positioning Actuators, 3 places

He Shroud

Chamber Lighting

Primary Mirror Cryogenic Tests
**XRCF Cryo Test**

- Survival Temperature
- Cryo Deployment
- Nominal Measurement
- Hexapod Deformation Pose
- RoC Actuation Test
- Hexapod Envelope Test
- Pullout Current & Redundant Test (3 of 6 PMSAs)
- Set RoC
- Nominal Measurement
- Hexapod Tilt Test
- Pullout Current & Redundant Test (3 of 6 PMSAs)

**Flight Mirrors in XRCF**
Lesson Learned

While Gravity is a significant problem for large mirrors.
It is also problem for lightweight mirrors in non-kinematic mounts

Once I had a task to test an ‘egg-crate’ 0.75 meter diameter flat mirror to 30 nm PV.

After initial characterization tests with the customer, I declined.
The customer provided ‘metrology’ mount was unsuitable.
The mirror was so ‘floppy’ (i.e. low stiffness) that simply picking it up and setting it back down onto the metrology mount resulted in a 100 nm PV shape change (both astigmatic bending and local mount stress).

Rule #6: Independent Cross-Checks

Probably the single most ‘famous’ lesson learned from Hubble is to never rely on a single test to certify a flight specification.

Every JWST optical component specification had a primary certification test and a confirming test.
Every Requirement has an Independent Validation

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<td>+/-</td>
<td>0.0005</td>
<td>Measured at cryo and defined by null geometry for XRCF CGH CoC test</td>
<td>Ambient test at Tinsley, compare CGH CoC test with auto-collimation test</td>
</tr>
<tr>
<td>Radius of Curvature</td>
<td>*</td>
<td>+/-</td>
<td>0.15</td>
<td>mm Set at XRCF using ADM</td>
<td>RCOO Comparison</td>
</tr>
<tr>
<td>Prescription Alignment Error</td>
<td>*</td>
<td>&lt;=</td>
<td>0.35</td>
<td>mm Cryogenic test at XRCF, defined by residual wavefront error relative to CGH CoC test and fiducial alignment</td>
<td>Ambient test at Tinsley, compare CGH CoC test with auto-collimation test</td>
</tr>
<tr>
<td>Decenter</td>
<td>0</td>
<td>&lt;=</td>
<td>0.35</td>
<td>mrad Ambient test at Tinsley</td>
<td></td>
</tr>
<tr>
<td>Clocking</td>
<td>0</td>
<td>&lt;=</td>
<td>0.35</td>
<td>mrad Ambient test at Tinsley</td>
<td></td>
</tr>
<tr>
<td>Piston</td>
<td>N/A</td>
<td></td>
<td></td>
<td>Ambient CMM measurement at AXSYS</td>
<td>Ambient CMM measurement at Tinsley</td>
</tr>
<tr>
<td>Tilt</td>
<td>N/A</td>
<td></td>
<td></td>
<td></td>
<td></td>
</tr>
<tr>
<td>Total Surface Figure Error</td>
<td>20</td>
<td>Max</td>
<td>nm</td>
<td>Cryo-Test at XRCF</td>
<td>Cryo-Test at JSC</td>
</tr>
<tr>
<td>Low/Mid Frequency</td>
<td>7</td>
<td>Max</td>
<td>nm</td>
<td>Thermal Test at XRCF</td>
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</tr>
<tr>
<td>High Frequency</td>
<td>4</td>
<td>Max</td>
<td>nm</td>
<td>Thermal Test at XRCF</td>
<td></td>
</tr>
<tr>
<td>Surface Roughness</td>
<td>4</td>
<td>Max</td>
<td>nm</td>
<td>Ambient Chapman measurement at Tinsley</td>
<td>NONE</td>
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</tbody>
</table>

Ball Optical Test Station (BOTS)

Tinsley ambient metrology results are ‘cross-checked’ at BATC
BOTS measurements:

- Measure Configuration 1 to 2 deformation
- Measure Configuration 2 to 3 deformation
- Create a Gravity Backout file for use at XRCF
- Measure Vibration Testing Deformation
- Measure Vacuum Bakeout Deformation
- Measure Configuration 2 mirrors for BATC to Tinsley Data Correlation

Diagram:

- Interferometer
- Environmental Enclosure
- 6 DOF Test Stand and Mirror
- CGH
- Enclosure Door
Auto-Collimation Test

Auto-Collimation Test provides independent cross-check of CGH Center of Curvature Test

Verifies:
- Radius of Curvature
- Conic Constant
- Off-Axis Distance
- Clocking

Note: is not a full-aperture figure verification test

Final Cross-Check performed at Observatory Level

<table>
<thead>
<tr>
<th>Johnson Space Center Chamber A</th>
<th></th>
</tr>
</thead>
<tbody>
<tr>
<td>Chamber size</td>
<td>16.7 meter diameter, 35.6 meter tall</td>
</tr>
<tr>
<td>Existing Shrouds</td>
<td>LN2 shroud, GHe panels</td>
</tr>
<tr>
<td>Chamber Cranes</td>
<td>4 x 7.6 meter fixed, removable</td>
</tr>
<tr>
<td>Chamber Door</td>
<td>12 meter diameter</td>
</tr>
<tr>
<td>High bay space</td>
<td>~31 m L x 21.6 m W</td>
</tr>
</tbody>
</table>
Rule #7: Understand All Anomalies

Of all the rules, this one maybe the most important and must be followed with independent rigor.

No matter how small, one must resist the temptation of sweeping a discrepancy under the metaphorical error budget rug.

Tinsley Test Reproducibility
(OTS-1 Test #1 vs. Test #2) VC6GA294-VC6HA270

Total Surface Delta:
PV: 373 nm
RMS: 7.6 nm

Power (Radius Delta: 0.02 mm)
Astigmatism: 4.4 nm RMS
Mid Frequency: 4.3 nm RMS
High Frequency: 3.9 nm RMS
Initially, BOTS and TOTS Radius did not agree. Discrepancy was determined to be caused by bulk temperature difference. Agreement is now at 10 nm rms level.

Lesson Learned: Clear Aperture Edge Specification

Center of Curvature test and High-Spatial Frequency test gave entirely different answers for compliance with Edge Requirement – 15 mm difference.

Which one was right had significant cost & schedule impact.

HS was right, CoC was wrong.

Problem was caused by depth of focus and Fresnel diffraction.
Conclusions

Based on 30 years of optical testing experience, I have defined seven guiding principles for optical testing.

- Fully Understand the Task
- Develop an Error Budget
- Continuous Metrology Coverage
- Know where you are
- ‘Test like you fly’
- Independent Cross-Checks
- Understand All Anomalies

With maybe an 8th of deliberately disturbing or randomizing the test.

JWST optical component in-process optical testing and cryogenic compliance certification, verification & validation was accomplished by a dedicated metrology team used these principles.

All JWST optical components meet their requirements.